

PATENT APPLICATION Docket No. 11675.114 HID B

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Kei-Yu Ko

O8/846,671

Filed:

April 30, 1997

For:

UNDOPED SILICON DIOXIDE AS ETCH STOP FOR SELECTIVE ETCH OF DOPED SILICON DIOXIDE

Examiner:

George A. Goudreau

AMENDMENT B UNDER 37 C.F.R. § 1.111

The Honorable Commissioner of Patents and Trademarks Washington, D. C. 20231

Sir:

In response to the Office Action mailed on February 17, 2000 (the "Office Action"), the Applicants submit this Amendment A and response.

IN THE CLAIMS

Amend Claims 1, 9, 13, 15, 18-23, 26, 30-34, 37, 39, 41-42, 44- 45, 50, and 53 as follows: